

**PATENT NUMBER and
ISSUE DATE**

U.S. UTILITY Patent Application

APPL NUM 10054962	FILING DATE 01/25/2002	CLASS 438	SUBCLASS 692	GAU 1765	EXAMINER UIC-6407, K
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****CONTINUING DATA VERIFIED:**

**** FOREIGN APPLICATIONS VERIFIED:**

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no		ATTORNEY DOCKET NO	
35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no		4006-150	
Verified and Acknowledged Examiners's initials			

TITLE : Method for controlling and monitoring a chemical mechanical polishing process

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	Print Claim for O.G.
Assistant Examiner			
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drawg.	Figs. Drawg.
		Print Fig.	
<input type="checkbox"/> TERMINAL DISCLAIMER BEST AVAILABLE		Primary Examiner	
		Application Examiner	
PREPARED FOR ISSUE			
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